

Notic of References Cited	Application/Control No. 10/040,420		Applicant(s)/Patent Under Reexamination POTYRAILO ET AL.	
	Examiner Manuel L. Barbee		Art Unit 2857	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-5,497,777	03-1996	Abdel-Malek et al.	600/443
	C	US-6,103,350	08-2000	Grangeat et al. ✓	428/195.1
*	D	US-5,619,998	04-1997	Abdel-Malek et al.	600/437
*	E	US-5,740,036	04-1998	Ahuja et al.	702/17
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.